

U.S. UTILITY PRIORITY APPLICATION

FA 500 (10)

APPLICATION NO. 09/811447	CONT/PRIOR F	CLASS 355	SUBCLASS 30	ART UNIT 2851	EXAMINER Matthew A. [Signature]
APPLICANTS Shuichi Yabu					
TITLE Exposure apparatus, gas replacing method, and method of manufacturing a semiconductor device					
PTO-20-01 12/03					

<p>Drawings</p> <p>20 25 1</p>	<p>Claims Allowed</p> <p>100% (20)</p>
<p>Notice of Allowance</p> <p>6-28-03</p>	<p>Amount Due</p> <p>\$1600.00</p>
<p>Issue Date</p> <p>6-28-03</p>	<p>Issue Batch Number</p> <p>1600-01</p>

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